

Session schedule of ISFA2022

Sunday, July 3rd			
JST <small>(Japan Standard Time)</small>	PDT <small>(US Pacific Daylight Time)</small>	EDT <small>(US Eastern Daylight Time)</small>	
16:00 – 17:00	0:00 – 1:00	3:00 – 4:00	Registration desk opens at Lobby, Raiosha
17:00 – 18:30	1:00 – 2:30	4:00 – 5:30	Welcome reception at Faculty lounge, Raiosha

Monday, July 4th			
JST	PDT	EDT	
8:30 –			Registration desk opens at Lobby, Raiosha
9:30 – 9:50	17:30 – 17:50	20:30 – 20:50	Opening address at Symposium space, Raiosha
9:50 – 10:50	17:50 – 18:50	20:50 – 21:50	Plenary Talk 1, Project Professor Kouhei Ohnishi, Keio University, KISTEC “Real Haptics Toward Smart Manufacturing” at Symposium space, Raiosha
10:50 – 11:00	18:50 – 19:00	21:50 – 22:00	Coffee break
11:00 – 12:00	19:00 – 20:00	22:00 – 23:00	Plenary Talk 2, Professor Masayoshi Tomizuka, University of California, Berkeley “Intelligent Decision Making and Control for Versatile and Flexible Handling of Tasks by Industrial Robots”
12:00 – 13:30	20:00 – 21:30	23:00 – 0:30	Lunch
13:30 – 15:10	21:30 – 23:10	0:30 – 2:10	OS 10-1 OS 10. Precision Manufacturing OS 3-1 OS 3. Digital Design and Manufacturing OS 4-1 OS 4. Flexible Automation in Manufacturing Systems
15:10 – 15:30	23:10 – 23:30	2:10 – 2:30	Coffee break
15:30 – 17:10	23:30 – 1:10	2:30 – 4:10	OS 2-1 OS 2. Cutting and Machine Tools OS 3-2 OS 3. Digital Design and Manufacturing OS 4-2 OS 4. Flexible Automation in Manufacturing Systems

Tuesday, July 5th			
JST	PDT	EDT	
8:00 –			Registration desk opens at Lobby, Raiosha
9:00 – 10:00	17:00 – 18:00	20:00 – 21:00	Plenary Talk 3, Dr. Koji Yasui, Mitsubishi Electric Corporation “Advanced Manufacturing Using IoT, AI, 5G/6G, and Quantum Technologies to Survive in A Sustainable Society, – Cooperation with Digital, Decarbonization, EV, Semiconductor, and Quantum Markets –” at Symposium space, Raiosha
10:00 – 10:20	18:00 – 18:20	21:00 – 21:20	Coffee break
10:20 – 12:00	18:20 – 20:00	21:20 – 23:00	OS 1-1 OS 1. Additive Manufacturing Sensing and Control OS 11-1 OS 11. Sensing and Information Extraction OS 4-3 OS 4. Flexible Automation in Manufacturing Systems
12:00 – 13:30	20:00 – 21:30	23:00 – 0:30	Lunch
13:30 – 14:50	21:30 – 22:50	0:30 – 1:50	OS 6-1 OS 6. Manufacturing Controls and Machine Automation OS 11-2 OS 11. Sensing and Information Extraction OS 8-1 OS 8. Metrology for Manufacturing
14:50 – 15:10	22:50 – 23:10	1:50 – 2:10	Coffee break
15:10 – 16:10	23:10 – 0:10	2:10 – 3:10	OS 6-2 OS 6. Manufacturing Controls and Machine Automation OS 8-2 OS 8. Metrology for Manufacturing
16:10 – 18:00	0:10 – 2:00	3:10 – 5:00	Break
18:00 – 20:00	2:00 – 4:00	5:00 – 7:00	Banquet at Hotel New Grand

Wednesday, July 6th			
JST	PDT	EDT	
8:00 –			Registration desk opens at Lobby, Raiosha
9:00 – 10:00	17:00 – 18:00	20:00 – 21:00	Plenary Talk 4, Professor Jianjun Shi, Georgia Institute of Technology “In-Process Quality Improvement (IPQI) Enhanced Automation in Smart Manufacturing” at Symposium space, Raiosha
10:00 – 10:20	18:00 – 18:20	21:00 – 21:20	Coffee break
10:20 – 12:00	18:20 – 20:00	21:20 – 23:00	OS 12-1 OS 12. Smart/Sustainable Manufacturing OS 5-1 OS 5. Industrial Robotics OS 7-1 OS 7. Mechatronics and Precision Manufacturing
12:10 – 13:00	20:10 – 21:00	23:10 – 0:00	Award Ceremony
13:00 – 13:20	21:00 – 21:20	0:00 – 0:20	Break
13:20 – 14:20	21:20 – 22:20	0:20 – 1:20	OS 12-2 OS 12. Smart/Sustainable Manufacturing OS 9-1 OS9. Nanomanufacturing and Nanoinformatics OS 7-2 OS 7. Mechatronics and Precision Manufacturing

Thursday, July 7th			
JST	PDT	EDT	
10:00 – 12:00	N/A	N/A	Technical Tour (Laboratory tour in Keio University)